

Docket No.: 50090-301

UTILITY PATENT APPLICATION  
UNDER 37 CFR 1.53(b)

Box PATENT APPLICATION  
Commissioner for Patents  
Washington, DC 20231  
Sir:

Transmitted herewith for filing is the patent application of:

INVENTOR: Toshihiro YAMASHITA, Hirotoshi ISE  
FOR: PLASMA PROCESSING SYSTEM IN WHICH WAFER IS RETAINED BY  
ELECTROSTATIC CHUCK, PLASMA PROCESSING METHOD AND  
METHOD OF MANUFACTURING SEMICONDUCTOR DEVICE

Enclosed are:

- ☒ 19 pages of specification, claims, abstract.
- ☒ Declaration and Power of Attorney.
- ☒ Priority Claimed.
- ☒ Certified copy of Japanese Patent Application No. 2000-403083
- ☒ 3 sheets of formal drawing.
- ☒ An assignment of the invention to Mitsubishi Denki Kabushiki Kaisha  
and the assignment recordation fee.
- ☐ An associate power of attorney.
- ☐ A verified statement to establish small entity status under 37 CFR 1.9 and 37 CFR 1.27.
- ☐ Information Disclosure Statement, Form PTO-1449 and reference.
- ☒ Return Receipt Postcard
- ☐

The filing fee has been calculated as shown below:

	NO. OF CLAIMS		EXTRA CLAIMS	RATE	AMOUNT
Total Claims	18	-20	0	\$18.00	\$0.00
Independent Claims	2	-3	0	\$80.00	\$0.00
Multiple Dependent Claim(s)					\$0.00
Basic Fee					\$710.00
Total of Above Calculations					\$710.00
Less ½ for Small Entity					\$0.00
Assignment & Recording Fee					\$40.00
Total Fee					\$750.00



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PATENT TRADEMARK OFFICE



